

UNISERS Ships First Fully-Automated Fab Tool and Strengthens Leadership to Scale In-Fab Deployment

Zurich, Switzerland – January 29, 2026 – UNISERS, a Zurich-based company advancing contamination control in semiconductor manufacturing, today announced a key commercial milestone: the sale and shipment of its first fully-automated, volume-production-ready fab tool to a leading-edge semiconductor manufacturer. The deployment marks the start of broader in-fab rollout discussions, with additional systems expected to follow.

In parallel, UNISERS has appointed Chuck Milligan as Chief Executive Officer and longtime KLA executive Oreste Donzella as Strategic Advisor, strengthening the leadership team as the company scales commercial adoption.

“Shipping our first fully-automated fab tool into a production environment is a major milestone for UNISERS,” said Ali Altun, cofounder and CTO. “It reflects years of work on a fundamentally new approach to detecting and classifying contamination at the molecular level and builds on the success of our lab tools already in customer use. With this system now operating in-fab, we’re taking a critical step toward high-volume manufacturing.”

Contamination-driven yield excursions remain one of the most expensive challenges in advanced semiconductor manufacturing, representing a 50-billion-dollar annual impact globally, with leading-edge nodes particularly affected. UNISERS addresses this challenge by delivering real-time, in-line visibility into particle sources and composition, both on wafers and in process liquids, enabling faster root-cause analysis and more effective advanced process control.

“With our first system now in a customer fab, UNISERS is moving from validation to scale,” said Milligan. “As device architectures shrink and process complexity increases, fabs need faster and more sensitive insight into contamination events. Our focus is on expanding in-fab deployments and delivering measurable yield improvements.”

“The industry needs constant innovation to improve in-line visibility of contamination events that drive yield excursions,” added Donzella. “UNISERS’ technology complements existing inspection and metrology tools, strengthening advanced process control where deeper insight is most needed.”

This first fab deployment marks UNISERS’ transition from lab and pilot environments into continuous, automated production use. In 2026, the company will focus on scaling its fab platform and expanding customer deployments.

About UNISERS

UNISERS AG is an ETH Zurich spinoff, incorporated in 2019 to revolutionize contamination control for optimized chip production yields. Its proprietary Surface

Enhanced Particle Sizing (SEPS) and Surface Enhanced Raman Spectroscopy (SERS) technologies enable unmatched nanoparticle detection and classification. UNISERS brings new analytical capabilities to semiconductor fabs, helping customers reduce yield losses, accelerate technology ramp-up, and advance more sustainable manufacturing practices.

For more information, visit www.unisers.ch.